SOS GROUP

LAM Research
4520 Oxide Etch 200mm Configuration
SN 3184

LAM Research
4520 Oxide Etch SN 3184
Location warehouse Nijmegen condition refurbished

Tool Model : 4520
Current Tool Serial Number : 3184
SoS dual LCD monitor upgrade
SoS Powersupply upgrade
New pneumatic lines
Bulkhead system mount w/tunnel covers
Hine 38A open cassette Send/Receive indexers
Software Version: Envision
Oxide etcher, 8” 4,5 and 6 inch optional
Clamp type/ ESC optional
RF power rack AE PDW 2200 watt RF generator
AC Rack AC Power Distribution
Moving gap
Back Helium Colling
Main Power 208V, 3 Phase, 5Wire, 175A, 60/
Belt driven load station
Standard load station shuttle spatula
Upper chamber gap drive encoder
Dip PCB for RF power tuning
Aluminum upper chamber electrode

Single lower chamber endpoint detector (405/520nm) Non-
Low pressure chamber manifold
HPS valve for chamber isolation
AC--2 chamber pressure control
Lower chamber RGA port
Millipore CMHT--11S02 10 Torr chamber manometer
Millipore CMLA--21 100 Torr backside helium manometer
Tylan General CMHT--11S02 10 Torr reference manometer
8 -- Gas box Orbital gas box
Gas 1: To custemer Spec
Gas 2: To custemer Spec
Gas 3: To custemer Spec
Gas 4: To custemer Spec
Gas 5: To custemer Spec
Gas 6: To custemer Spec
Gas 7: To custemer Spec
Gas 8: To custemer Spec
UPC: He (50 sccm) -- Unit 1300
AC input box for AC power inlet
Trip breakers AC/DC power box

LAM Research
4520 Oxide Etch SN 3184
Location warehouse Nijmegen condition refurbished

SOS GROUP

Solutions on Silicon BV

Your service partner for LAM Research Equipment

- **Equipment Support**
  PM, CM, Trouble shooting, Upgrading, Training and Onsite Service Contracts

- **Process Support**
  Process design, Improvement,
  Fab-to-Fab Transfer and Integration

- **Refurbishment**
  From custom to complete refurbishment

- **Relocation**
  Auditing, Fingerprinting, Decommissioning, Installation, Acceptance

- **Materials**
  Supplier of first class second source materials

www.Solutions-on-Silicon.com